

Notice of References Cited	Application/Control No. 10/718,126	Applicant(s)/Patent Under Reexamination NIKOONAHAD ET AL.	
	Examiner Hoa Q. Pham	Art Unit 2877	Page 1 of 2

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	"OPTICAL METROLOGY ROADMAP FOR THE SEMICONDUCTOR, OPTICAL AND DATA STORAGE INDUSTRIES", WOOLLAM ET AL., PROC. OF SPIE., VOL 4099, (JULY 2000).
	V	"SPECTROSCOPIC ELLIPSOMETRY FROM THE VACUUM ULTRAVIOLET TO THE FAR INFRARED", WOOLLAM ET AL., CHARACTERIZATION AND METROLOGY FOR ULSI TECHNOLOGY: 2000 INTERNATIONAL CONFERENCE.
	W	"CHARACTERIZATION OF THIN FILMS AND MULTILAYERS IN THE VUV WAVELENGTH RANGE USING SPECTROSCOPIC ELLIPSOMETRY AND SPECTROSCOPIC PHOTOMETRY" BOHER ET AL., 157 NM SYMPOSIUM, (MAY 2000).
	X	"MATERIALS CHARACTERIZATION IN THE VACUUM ULTRAVIOLET WITH VARIABLE ANGLE SPECTROSCOPIC ELLIPSOMETRY", WAGNER ET AL., PHYS. STAT. SOL. (a) 188, No. 4, (2001).

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.

Notice of References Cited	Application/Control No. 10/718,126	Applicant(s)/Patent Under Reexamination NIKOONAHAD ET AL.	
	Examiner Hoa Q. Pham	Art Unit 2877	Page 2 of 2

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	"IN SITU MONITORING OF GaN METAL-ORGANIC VAPOR PHASE EPITAXY BY SPECTROSCOPIC ELLIPSOMETRY", PETERS, J. APP. PHYS., VOL. 88, NO. 7, (OCT. 2000).
	V	"ORDINARY AND EXTRAORDINARY DIELECTRIC FUNCTIONS OF 4H- AND 6H-SIC FROM 3.5 TO 9.0 EV", LINDQUIST ET AL., APP. PHYS. LETT., VOL 78, NO. 18 (APR. 2001).
	W	"PRECISE CHARACTERIZATION OF RESISTS AND IN THE VUV RANGE FOR 157 NM LITHOGRAPHY", BOJER ET AL., MAT. RES SOC. SYMP., VOL 636, (2001).
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.